Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S1	762	(mirror or reflector) with curv$ with (tilt$6 or pivot$6)	US-PGPUB; USPAT	OR	ON	2004/08/28 13:33
S2	345	S1 and ("385"/$.ccls. or "359"/$.ccls.)	US-PGPUB; USPAT	OR	ON	2004/08/28 13:34
S3	141	S2 and (layer$6 or substrat$6)	US-PGPUB; USPAT	OR	ON	2004/11/16 14:11
S4	1	"20030138213" and (actuat$6 with layer)	US-PGPUB; USPAT	OR	ON	2004/11/29 11:25
S5	0	(MEM with dop$6 with curv$6) same mirror	USPAT	OR	ON	2004/01/09 10:39
S6	106	MEM with dop$6	USPAT	OR	ON	2004/01/09 10:28
S7	18	(MEM with dop$6) and (mirror or relect$6)	USPAT	OR	ON	2003/09/12 15:23
S8	1	MEM with dop$6 with curv$6	USPAT	OR	ON	2003/09/12 15:23
S9	1	((MEMS or MOEMS) same (mirror$4 or reflect$7 or HR)) and ((mirror$4 or reflect$7 or HR) with (micrometer or ".mu."$8)) and (curvature with radius)	USPAT	OR	ON	2004/01/08 11:41
S10	9	((MEMS or MOEMS) same (mirror$4 or reflect$7 or HR)) and ((mirror$4 or reflect$7 or HR) with (micrometer or ".mu."$8)) and (curvature with radius)	US-PGPUB; USPAT	OR	ON	2004/08/28 13:30
S11	1	"20030138213"	US-PGPUB; USPAT	OR	ON	2004/01/08 11:51
S12	9	((MEMS or MOEMS) same (mirror$4 or reflect$7 or HR)) and ((mirror$4 or reflect$7 or HR) with (micrometer or ".mu.m")) and (curvature with radius)	US-PGPUB; USPAT	OR	ON	2004/01/08 12:56
S13	7	(((MEMS or MOEMS) same (mirror$4 or reflect$7 or HR)) and ((mirror$4 or reflect$7 or HR) with (micrometer or ".mu.m")) and (curvature with radius)) and "mu.m"	US-PGPUB; USPAT	OR	ON	2004/01/08 12:56
S14	7	(((MEMS or MOEMS) same (mirror$4 or reflect$7 or HR)) and ((mirror$4 or reflect$7 or HR) with (micrometer or ".mu.m")) and (curvature with radius)) and "mu.m"$8	US-PGPUB; USPAT	OR	ON	2004/01/10 17:33
S15	1	"6525880".pn.	US-PGPUB; USPAT	OR	ON	2004/01/08 14:27
S16	2	(coat$6 with layer$6) and (MEMS or MOEMS) and ((process or method) with (mak$6 orfabricat$6 or manufactur$6)) and (etch$8 with layer$6) and (dop$6 with curv$7)	USPAT	OR	ON	2004/01/09 10:14

S17	5	(coat$6 with layer$6) and (MEMS or MOEMS) and ((process or method) with (mak$6 orfabricat$6 or manufactur$6)) and (etch$8 with layer$6) and (dop$6 with curv$7)	US-PGPUB; USPAT	OR	ON	2004/01/09 10:15
S18	8	(coat$6 with layer$6) and (MEMS or MOEMS) and ((process or method) with (mak$6 or fabricat$6 or manufactur$6)) and (etch$8 with layer$6) and (dop$6 with curv$7)	US-PGPUB; USPAT	OR	ON	2004/08/28 15:00
S19	1	((MEM or MOEM) with dop$6) with ((curv$6 or bend$6) with (substrat$6 or wafer$6))	USPAT	OR	ON	2004/01/09 10:45
S20	510	(coat$6 with layer$6) and (MEMS or MOEMS) and ((process or method) with (mak$6 or fabricat$6 or manufactur$6)) and (etch$8 with layer$6)	USPAT	OR	ON	2004/01/09 10:31
S21	1005	(coat$6 with layer$6) and (MEMS or MOEMS) and ((process or method) with (mak$6 or fabricat$6 or manufactur$6)) and (etch$8 with layer$6)	US-PGPUB; USPAT	OR	ON	2004/01/09 10:45
S22	22	(MEMS or Moems) and (dop$6 with curvature)	US-PGPUB; USPAT	OR	ON	2004/01/09 10:40
S23	161	(coat$6 with layer$6) and (MEMS or MOEMS) and ((process or method) with (mak$6 or fabricat$6 or manufactur$6)) and (etch$8 with layer$6) and ((curv$6 or bend$6) with (substrat$6 or wafer$6))	US-PGPUB; USPAT	OR	ON	2004/01/09 11:07
S24	123	((coat$6 with layer$6) and (MEMS or MOEMS) and ((process or method) with (mak$6 or fabricat$6 or manufactur$6)) and (etch$8 with layer$6) and ((curv$6 or bend$6) with (substrat$6 or wafer$6))) and (mirror$4 or reflect$8)	US-PGPUB; USPAT	OR	ON	2004/01/09 11:07
S25	51	((coat$6 with layer$6) and (MEMS or MOEMS) and ((process or method) with (mak$6 or fabricat$6 or manufactur$6)) and (etch$8 with layer$6) and ((curv$6 or bend$6) with (substrat$6 or wafer$6))) and (mirror$4 or reflect$8) and (dop$6 same substrate)	US-PGPUB; USPAT	OR	ON	2004/01/09 11:25
S26	25	ryf.in.	US-PGPUB; USPAT	OR	ON	2004/01/09 14:09
S27	1	"5618474".pn.	US-PGPUB; USPAT	OR	ON	2004/01/09 14:09

S28	6221	((coeff$8 with therm$6 with expan$6) or CTE) with silicon	US-PGPUB; USPAT	OR	ON	2004/01/10 17:34
S29	175	((coeff$8 with therm$6 with expan$6) or CTE) with silicon with value	US-PGPUB; USPAT	OR	ON	2004/01/10 17:39
S30	395	((coeff$8 with therm$6 with expan$6) or CTE) with gold	US-PGPUB; USPAT	OR	ON	2004/01/10 17:47
S31	15	((coeff$8 with therm$6 with expan$6) or CTE) same (dielectric$6 with (layer$4 or stack$6) with mirror)	US-PGPUB; USPAT	OR	ON	2004/01/10 18:16
S32	1	"6525880".pn.	US-PGPUB; USPAT	OR	ON	2004/11/29 10:29
S33	1	"6525880".pn. and (mirror same coat$6)	US-PGPUB; USPAT	OR	ON	2004/01/10 18:13
S34	1558	mirror with coat$6 with dielectric	US-PGPUB; USPAT	OR	ON	2004/01/10 18:14
S35	144	(mirror with coat$6 with dielectric) and "385"/$.ccls.	US-PGPUB; USPAT	OR	ON	2004/01/10 18:14
S36	46	(mirror with coat$6 with dielectric) and (mirror same (coeff$8 with therm$6 with expan$6))	US-PGPUB; USPAT	OR	ON	2004/01/10 18:17
S37	2488	385/16.ccls. or 385/18.ccls. or 385/47. ccls. or 359/578.ccls.	US-PGPUB; USPAT	OR	ON	2004/01/10 19:10
S38	42	(fabry with perot with cavity) and (radius near2 curvature with (mm or millimeter))	US-PGPUB; USPAT	OR	ON	2004/11/16 13:43
S39	21	(fabry with perot with cavity) and (radius near2 curvature with (mm or millimeter)) and (micrometers or mu)	US-PGPUB; USPAT	OR	ON	2004/11/16 13:40
S40	1	"20030138213"	US-PGPUB; USPAT	OR	ON	2004/11/16 13:43
S41	0	("2003/0138213").URPN.	USPAT	OR	OFF	2004/11/16 13:44
S42	789	(mirror or reflector) with curv$ with (tilt$6 or pivot$6)	US-PGPUB; USPAT	OR	ON	2004/11/16 14:11
S43	364	S42 and ("385"/$.ccls. or "359"/$.ccls.)	US-PGPUB; USPAT	OR	ON	2004/11/16 14:11
S44	16	S43 and (layer$6 or substrat$6) and (dop$6)	US-PGPUB; USPAT	OR	ON	2004/11/16 14:12
S45	1	"6594059".pn.	US-PGPUB; USPAT	OR	ON	2004/11/29 10:39
S46	1	"20030011864"	US-PGPUB; USPAT	OR	ON	2004/11/29 11:03
S47	0	sag with curvature with mirror same MEMS	US-PGPUB; USPAT	OR	ON	2004/11/29 11:04
S48	0	sag$6 with curv$7 with (mirror$6 or reflect$6) same MEMS	US-PGPUB; USPAT	OR	ON	2004/11/29 11:05

S49	6	sag$6 with curv$7 with (mirror$6 or reflect$6) and MEMS	US-PGPUB; USPAT	OR	ON	2004/11/29 11:09
S50	149	sag$6 with curv$7 with (mirror$6 or reflect$6)	US-PGPUB; USPAT	OR	ON	2004/11/29 11:09
S51	143	S50 not S49	US-PGPUB; USPAT	OR	ON	2004/11/29 11:09
S52	2	spoil$6 with sag$6 with cavity same (mirror$6 or reflect$6)	US-PGPUB; USPAT	OR	ON	2004/11/29 11:35
S53	35	(mems with fabry) and ((mirror$6 or reflect$6) with (mm or nm or micrometer or millimeter or nanometer))	US-PGPUB; USPAT	OR	ON	2004/11/29 11:58
S54	324	fabry with cavity with length same (mirror$6 or reflect$6)	US-PGPUB; USPAT	OR	ON	2004/11/29 11:59
S55	50	fabry with cavity with length same (mirror$6 or reflect$6) same (mm or nm or micrometer or millimeter or nanometer)	US-PGPUB; USPAT	OR	ON	2004/11/29 12:00